

Form PTO-1449 (modified)

List of Patents and Publications of Applicant's

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Atty. Docket No.

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09/911,264

Applicant

Richard J. Markle and Robert J. Chong

Filing Date:

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Group:

1762

U.S. Patent Documents

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Foreign Patent Documents

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Other Art

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U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
	A1						
	A2						
	A3						
	A4						
	A5						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1						
	B2						
	B3						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
LV	C1	Christel <i>et al.</i> , "Single-Crystal Silicon Pressure Sensors with 500 × Overpressure Protection," <i>Sensors and Actuators</i> , A21-A23:84-88, 1990
	C2	Guckel, "Surface Micromachined Pressure Transducers," <i>Sensors and Actuators</i> , A28:133-46, 1991
	C3	Ko <i>et al.</i> , "A High Sensitivity Integrated-Circuit Capacitive Pressure Transducer," <i>IEEE Transactions on Electron Devices</i> , ED-29:48-56, 1982
	C4	Lee and Wise, "A Batch-Fabricated Silicon Capacitive Pressure Transducer with Low Temperature Sensitivity," <i>IEEE Transactions on Electron Devices</i> , ED-29:42-48, 1982
	C5	Mallon <i>et al.</i> , "Low-Pressure Sensors Employing Bossed Diaphragms and Precision Etch-Stopping," <i>Sensors and Actuators</i> , A21-A23:89-95, 1990
LV	C6	Sander <i>et al.</i> , "A Monolithic Capacitive Pressure Sensor with Pulse-Period Output," <i>IEEE Transactions on Electron Devices</i> , ED-27:927-30, 1980

EXAMINER:

LAN VINH

DATE CONSIDERED:

11/25/00

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